

# **Atmospheric Substrate Processing Apparatus for Depositing Multiple Layers on a Substrate**

## **ABSTRACT OF THE DISCLOSURE**

A substrate processing apparatus is disclosed. In one embodiment, the apparatus includes a first atmospheric deposition station and a second atmospheric deposition station. The second atmospheric deposition station comprises an atmospheric pressure vapor deposition chamber. A substrate handling system is adapted to transfer substrates between the first and the second atmospheric deposition stations.

SF 1200876 v1